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INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(PTO-1449)



ATTY. DOCKET NO.
5198/Consolidated

SERIAL NO.
09/800,980

APPLICANT
Parris C.M. HAWKINS et al.

FILING DATE
March 8, 2001

GROUP
2121

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	4,796,194	01/03/89	Atherton			08/20/86
	5,089,970	02/18/92	Lee et al.			10/05/89
	5,108,570	04/28/92	Wang			03/30/90
	5,236,868	08/17/93	Nulman			04/20/90
	5,260,868	11/09/93	Gupta et al.			10/15/91
	5,295,242	03/15/94	Mashruwala et al.			11/02/90
	5,309,221	05/03/94	Fischer et al.			12/31/91
	5,367,624	11/22/94	Cooper			06/11/93
	5,398,336	03/14/95	Tantry et al.			06/16/93
	5,402,367	03/28/95	Sullivan et al.			07/19/93
	5,408,405	04/18/95	Mozumder et al.			09/20/93
	5,410,473	04/25/95	Kaneko et al.			12/16/92
	5,490,097	02/06/96	Swenson et al.			08/06/93
	5,629,216	05/13/97	Wijaranakula et al.			02/27/96

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
	HEI 1-283934	11/15/89	Japan			X	
	HEI 8-149583	06/07/96	Japan			X	
	HEI 9-34535	02/07/97	Japan			X	
	EP-0877308	11/11/98	Europe			X	
	HEI 11-67853	03/09/99	Japan			X	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

Dishon, G., D. Eylon, M. Finarov, and A. Shulman. "Dielectric CMP Advanced Process Control Based on Integrated Monitoring." Ltd. Rehoveth, Israel: Nova Measuring Instruments.

Runyan, W. R., and K. E. Bean. 1990. "Semiconductor Integrated Circuit Processing Technology." pg. 48. Reading, Massachusetts: Addison-Wesley Publishing Company.

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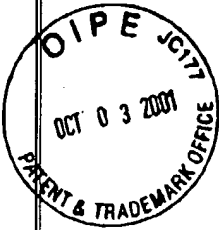
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U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	5,661,669	08/26/97	Mozumder et al.			06/07/95
	5,698,989	12/16/97	Nulman			09/13/96
	5,719,495	02/17/98	Mosleh			06/05/96
	5,740,429	04/14/98	Wang et al.			07/07/95
	5,751,582	05/12/98	Saxena et al.			09/24/96
	5,754,297	05/19/98	Nulman			04/14/97
	5,764,543	06/09/98	Kennedy			06/16/95
	5,808,303	09/15/98	Schlagheck et al.			01/29/97
	5,883,437	03/16/99	Maruyama et al.			12/28/95
	5,910,011	06/08/99	Cruse			05/12/97
	6,054,379	04/25/00	Yau et al.			02/11/98

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- B — Zorich, Robert. 1991. *Handbook of Quality Integrated Circuit Manufacturing*. pp. 464-498 San Diego, California: Academic Press, Inc.
- B — Rampalli, Prasad, Arakere Ramesh, and Nimish Shah. 1991. CEPT—A Computer-Aided Manufacturing Application for Managing Equipment Reliability and Availability in the Semiconductor Industry. New York, New York: IEEE.
- B — Moyne, James R., Nauman Chaudhry, and Roland Telfeyan. 1995. "Adaptive Extensions to a Multi-Branch Run-to-Run Controller for Plasma Etching." *Journal of Vacuum Science and Technology*. Ann Arbor, Michigan: University of Michigan Display Technology Manufacturing Center.
- B — Moyne, James, Roland Telfeyan, Arnon Hurwitz, and John Taylor. August 1995. "A Process-Independent Run-to-Run Controller and Its Application to Chemical-Mechanical Planarization." *SEMI/IEEE Advanced Semiconductor Manufacturing Conference and Workshop*. Ann Arbor, Michigan: The University of Michigan, Electrical Engineering & Computer Science Center for Display Technology & Manufacturing.

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U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT APPLICATION NO.	FILING DATE	NAME	TITLE	CLASS	SUB-CLASS
	09/363,966	07/29/99	Arackaparambil et al.	Computer Integrated Manufacturing Techniques		
	09/469,227	12/22/99	Somekh et al.	Multi-Tool Control System, Method and Medium		
	09/619,044	07/19/00	Yuan	System and Method of Exporting or Importing Object Data in a Manufacturing Execution System		
	09/637,620	08/11/00	Chi et al.	Generic Interface Builder		
	09/656,031	09/06/00	Chi et al.	Dispatching Component for Associating Manufacturing Facility Service Requestors with Service Providers		

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUB-CLASS	Translation
						Yes No

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

	Dishon, G., M. Finarov, R. Kipper, J.W. Curry, T. Schraub, D. Trojan, 4 th Stambaugh, Y. Li and J. Ben-Jacob. February 1996. "On-Line Integrated Metrology for CMP Processing." Santa Clara, California: VMIC Speciality Conferences, 1 st International CMP Planarization Conference.
	SEMI. [1986] 1996. "Standard for Definition and Measurement of Equipment Reliability, Availability, and Maintainability (RAM)." SEMI E10-96.
	Van Zant, Peter. 1997. <i>Microchip Fabrication: A Practical Guide to Semiconductor Processing</i> . Third Edition, pp. 472-478. New York, New York: McGraw-Hill.
	Campbell, W. Jarrett, and Anthony J. Toprac. February 11-12, 1998. "Run-to-Run Control in Microelectronics Manufacturing." Advanced Micro Devices, TWMCC.
	Consilium. August 1998. <i>Quality Management Component: QMC™ and QMC-Link™ Overview</i> . Mountain View, California: Consilium, Inc.
	Consilium. 1998. <i>FAB300™</i> . Mountain View, California: Consilium, Inc.
	Khan, Kareemullah, Victor Solakhain, Anthony Ricci, Tier Gu, and James Moyne. 1998. "Run-to-Run Control of ITO Deposition Process." Ann Arbor, Michigan.
	Moyne, James and John Curry. June 1998. "A Fully Automated Chemical-Mechanical Planarization Process."

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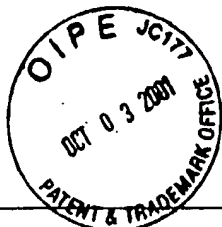
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U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT APPLICATION NO.	FILING DATE	NAME	TITLE	CLASS	SUB-CLASS
	09/655,542	09/06/00	Yuan	System, Method and Medium for Defining Palettes to Transform an Application Program Interface for a Service		
	09/725,908	11/30/00	Chi et al.	Dynamic Subject Information Generation in Message Services of Distributed Object Systems		

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUB-CLASS	Translation	
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OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

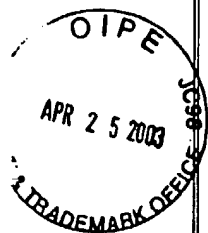
	SEMI July 1998. New Standard Provisional Specification for CIM Framework Domain Architecture. Mountain View, California: SEMI Standards. SEMI Draft Doc. 2817.
	Consilium. July 1999. "Increasing Overall Equipment Effectiveness (OEE) in Fab Manufacturing by Implementing Consilium's Next-Generation Manufacturing Execution System - MES II." Semiconductor Fabtech Edition 10.
	Consilium Corporate Brochure. October 1999. www.consilium.com
	Consilium. January 1999. "FAB300™: Consilium's Next Generation MES Solution of Software and Services which Control and Automate Real-Time FAB Operations." www.consilium.com/products/fab300_page.htm#FAB300 Introduction
	Consilium. November 1999. FAB300™ Update.
	SEMI. 2000. "Provisional Specification for CIM Framework Scheduling Component." San Jose, California. SEMI E105-1000.

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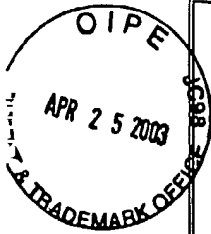
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	3,229,198	01/11/66	Libby			09/28/62
	4,000,458	12/28/76	Miller et al.			08/21/75
	4,302,721	11/24/81	Urbanek et al.			05/15/79
	4,750,141	06/07/88	Judell et al.			11/26/85
	4,757,259	07/12/88	Charpentier			11/05/86
	4,938,600	07/03/90	Into			02/09/89
	5,283,141	02/01/94	Yoon et al.			03/05/92
	5,338,630	08/16/94	Yoon et al.			11/18/93
	5,485,082	01/16/96	Wisspeintner et al.			04/05/90
	5,497,381	03/05/96	O'Donoghue et al.			06/01/95
	5,511,005	04/23/96	Abbe et al.			02/16/94
	5,519,605	05/21/96	Cawfield			10/24/94
	5,526,293	06/11/96	Mozumder et al.			12/17/93
	5,541,510	06/30/96	Danielson			04/06/95
	5,546,312	08/13/96	Mozumder et al.			02/24/94
	5,553,195	09/03/96	Meijer			09/29/94
	5,602,492	02/11/97	Cresswell et al.			04/28/94
	5,617,023	04/01/97	Skalski			02/02/95
	5,627,083	05/06/97	Tounai			05/12/95
	5,642,296	06/24/97	Saxena			07/29/93
	5,646,870	07/08/97	Krivokapic et al.			02/13/95
	5,649,169	07/15/97	Berezin et al.			06/20/95
	5,654,903	08/05/97	Reitman et al.			11/07/95
	5,663,797	09/02/97	Sandhu			05/16/96
	5,665,199	09/09/97	Sahota et al.			06/23/95
	5,666,297	09/09/97	Britt et al.			05/13/94

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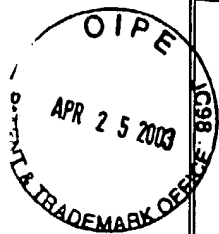
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	5,667,424	09/16/97	Pan			09/25/96
	5,674,787	10/07/97	Zhao et al.			01/16/96
	5,719,796	02/17/98	Chen			12/04/95
	5,735,055	04/07/98	Hochbein et al.			04/23/96
	5,761,064	06/02/98	La et al.			10/06/95
	5,777,901	07/07/98	Berezin et al.			09/29/95
	5,787,021	07/28/98	Samaha			12/18/95
	5,787,269	07/28/98	Hyodo			09/19/95
	5,825,913	10/20/98	Rostami et al.			07/18/95
	5,857,258	01/12/99	Penzes et al.			05/12/94
	5,910,846	06/08/99	Sandhu			08/19/97
	5,943,237	08/24/99	Van Boxem			10/17/97
	5,960,185	09/28/99	Nguyen			06/24/96
	5,961,369	10/05/99	Bartels et al.			06/04/98
	5,978,751	11/02/99	Pence et al.			02/25/97
	6,017,771	01/25/00	Yang et al.			04/27/98
	6,036,349	03/14/00	Gombar			07/26/96
	6,064,759	05/16/00	Buckley et al.			11/06/97
	6,072,313	06/06/00	Li et al.			06/17/97
	6,097,887	08/01/00	Hardikar et al.			10/27/97
	6,108,092	08/22/00	Sandhu			06/08/99
	6,127,263	10/03/00	Parikh			07/10/98
	6,136,163	10/24/00	Cheung et al.			03/05/99
	6,141,660	10/31/00	Bach et al.			07/16/98
	6,143,646	11/07/00	Wetzel			06/03/97
	6,148,099	11/14/00	Lee et al.			07/03/97
	6,148,239	11/14/00	Punk et al.			12/12/97
EXAMINER	DATE CONSIDERED 6/23/01					

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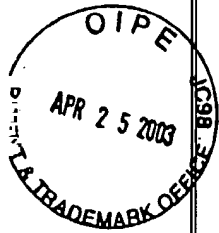
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U.S. PATENT DOCUMENTS

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	6,159,075	12/12/00	Zhang			10/13/99
	6,159,644	12/12/00	Sato et al.			03/06/96
	6,161,054	12/12/00	Rosenthal et al.			09/17/98
	6,169,931	01/02/01	Runnels			06/29/98
	6,172,756	01/09/01	Chalmers et al.			12/11/98
	6,173,240	01/09/01	Sepulveda et al.			11/02/98
	6,191,864	02/20/01	Sandhu			02/29/00
	6,204,165	03/20/01	Ghoshal			06/24/99
	6,210,983	04/03/01	Atchison et al.			06/15/99
	6,214,734	04/10/01	Bothra et al.			11/20/98
	6,217,412	04/17/01	Campbell et al.			08/11/99
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	6,246,972	06/12/01	Klimasauskas			05/27/99
	6,276,989	08/21/01	Campbell et al.			08/11/99
	6,280,289	08/28/01	Wiswesser et al.			11/02/98
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	6,320,655	11/20/01	Matsushita et al.			03/15/00
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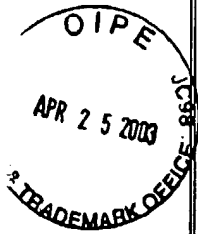
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	2001/0042690	11/22/01	Tatich			12/14/00
	6,324,481	11/27/01	Atchison et al.			06/15/99
	6,334,807	01/01/02	Lebel et al.			04/30/99
	6,336,841	01/08/02	Chang			03/29/01
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	2002/0102853	08/01/02	Li et al.			12/20/01
	2002/0107599	08/08/02	Patel et al.			01/25/01
	6,435,952	08/20/02	Boyd et al.			06/30/00
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	2002/0113039	08/22/02	Mok et al.			02/16/01
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	2002/0127950	09/12/02	Hirose et al.			03/08/01
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	2002/0149359	10/17/02	Crouzen et al.			08/18/01
	6,479,902	11/12/02	Lopatin et al.			06/29/00
	6,479,990	11/12/02	Mednikov et al.			06/18/01
	2002/0185658	12/12/02	Inoue et al.			06/14/01
	2002/0193902	12/19/02	Shanmugasundram et al.			06/18/02
	2002/0197745	12/26/02	Shanmugasundram et al.			08/31/01
	2002/0197934	12/26/02	Paik			11/30/01
	2002/0199082	12/26/02	Shanmugasundram et al.			06/18/02
	6,503,839	01/07/03	Gonzales et al.			07/03/01
	2003/0020909	01/30/03	Adams et al.			04/09/01
	2003/0020928	01/30/03	Ritzdorf et al.			07/09/01
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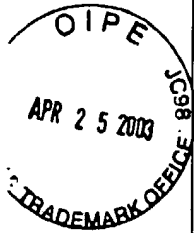
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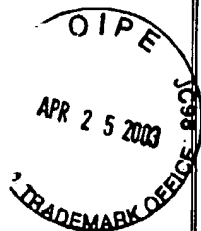
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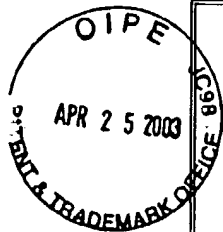
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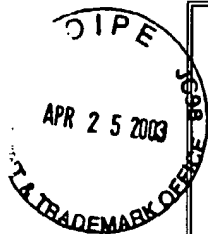
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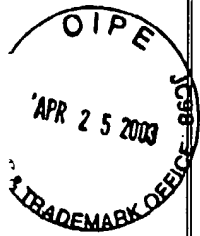
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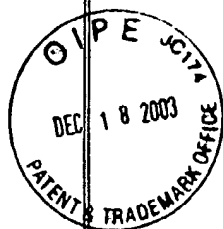
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**INFORMATION DISCLOSURE
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(PTO-1449)**

ATTY. DOCKET NO.
005198
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SERIAL NO.
09/800,980

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APPLICANT
Parris C.M. HAWKINS et al.

Technology Center 2100

FILING DATE
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GROUP
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APPLICANT
Parris C.M. HAWKINS et al.

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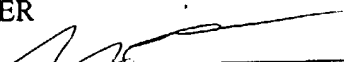
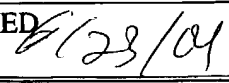
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APPLICANT Parris C.M. HAWKINS et al.				FILING DATE March 8, 2001		GROUP 2121	
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